

Cathodoluminescence Study of Acceptor- and Donor-related Emission of ZnO or ZnO:N Films Annealed Under O₂ or N₂ Atmosphere



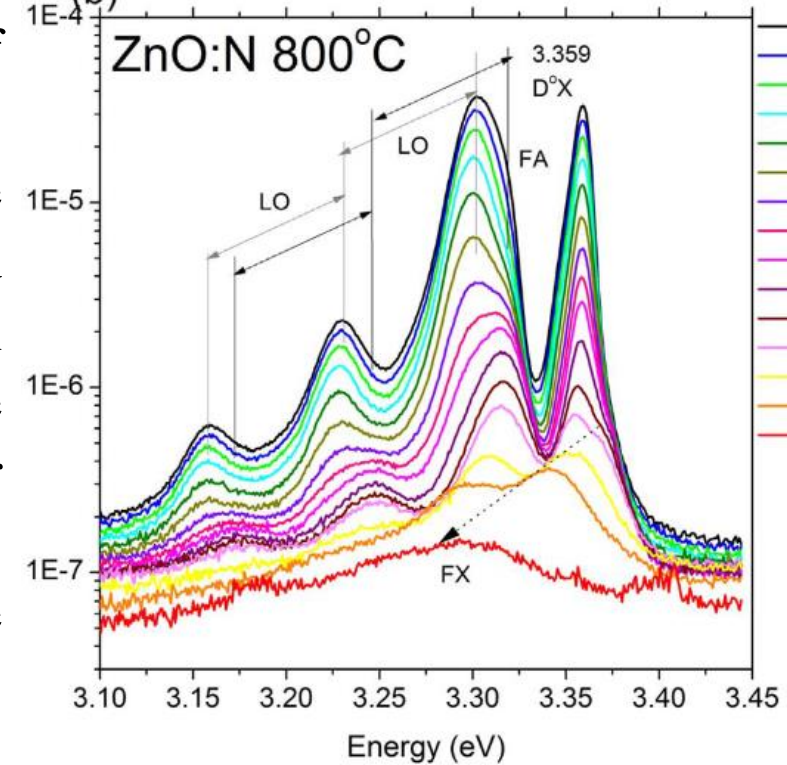
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Motivation

Worldwide efforts are being made to better understand the activation of acceptor states in ZnO, with the goal of achieving long-desired persistent *p*-type conductivity. Annealing study was performed to better understand the variation in acceptor- or donor-related emission in polycrystalline ZnO and ZnO:N, because annealing at different temperature and atmosphere can simultaneously activate acceptors and decrease structural disorder. We compared 1.5 micron thick ZnO and ZnO:N films deposited by Atomic Layer Deposition (ALD) on HR-Si (100) under O-rich conditions (100°C) and post-growth annealed at 6 different temperatures 400-900°C under N₂/O₂ atm. The intensity of acceptor-related and donor-related cathodoluminescence (CL), impurities concentration, structure of the films and RT-Hall have been investigated after different type of annealing. The experiment was carried out for N concentrations ranging from 10¹⁷ to 10¹⁹ at/cm³.



Ref: Przędzicka, Guzewicz & Witkowski (2018) Journal of Luminescence, 198, 68-76.

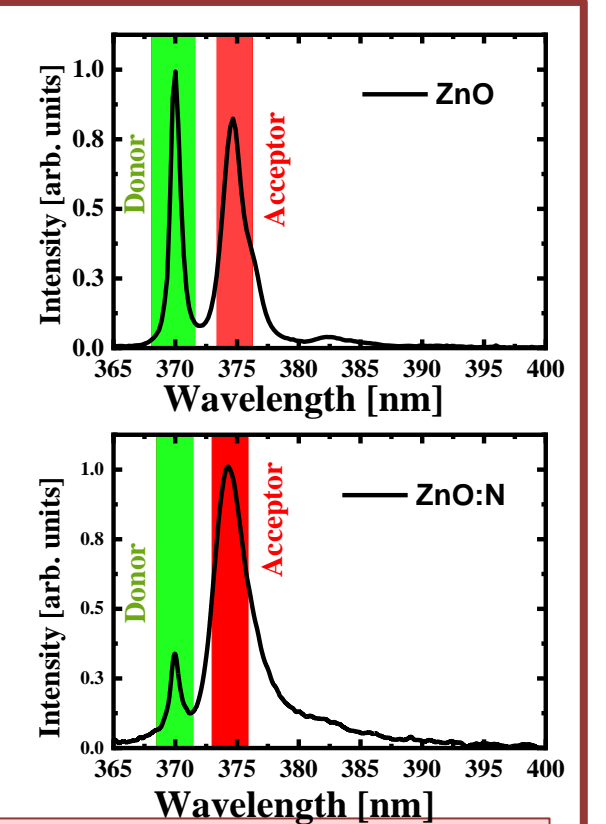
Low Temperature Cathodoluminescence with SEM Mapping

Excitation and recombination of electron-hole pairs drive CL emission in semiconductors. The CL maps can be used to detect radiative and non-radiative area of the film by scanning the incident beam across the sample.

In the experiment, we recorded the CL maps from the ZnO and ZnO:N films cross-sections in order to investigate the spatial distribution of acceptor-related emission.

In case of ZnO and ZnO:N, the LT-CL spectroscopy can determine the status of acceptor or donor-related emission on given cross-section of SEM-image. To distinguish between optically active acceptor or donor-related luminescence, LT-CL spectra were recorded at different cross-sections of ZnO and ZnO:N layers in the near band edge emission spectral region.

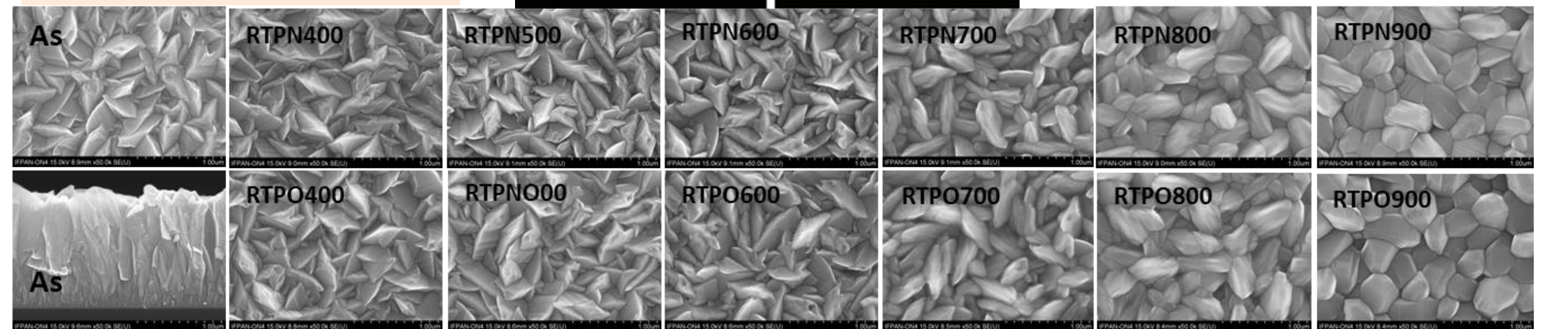
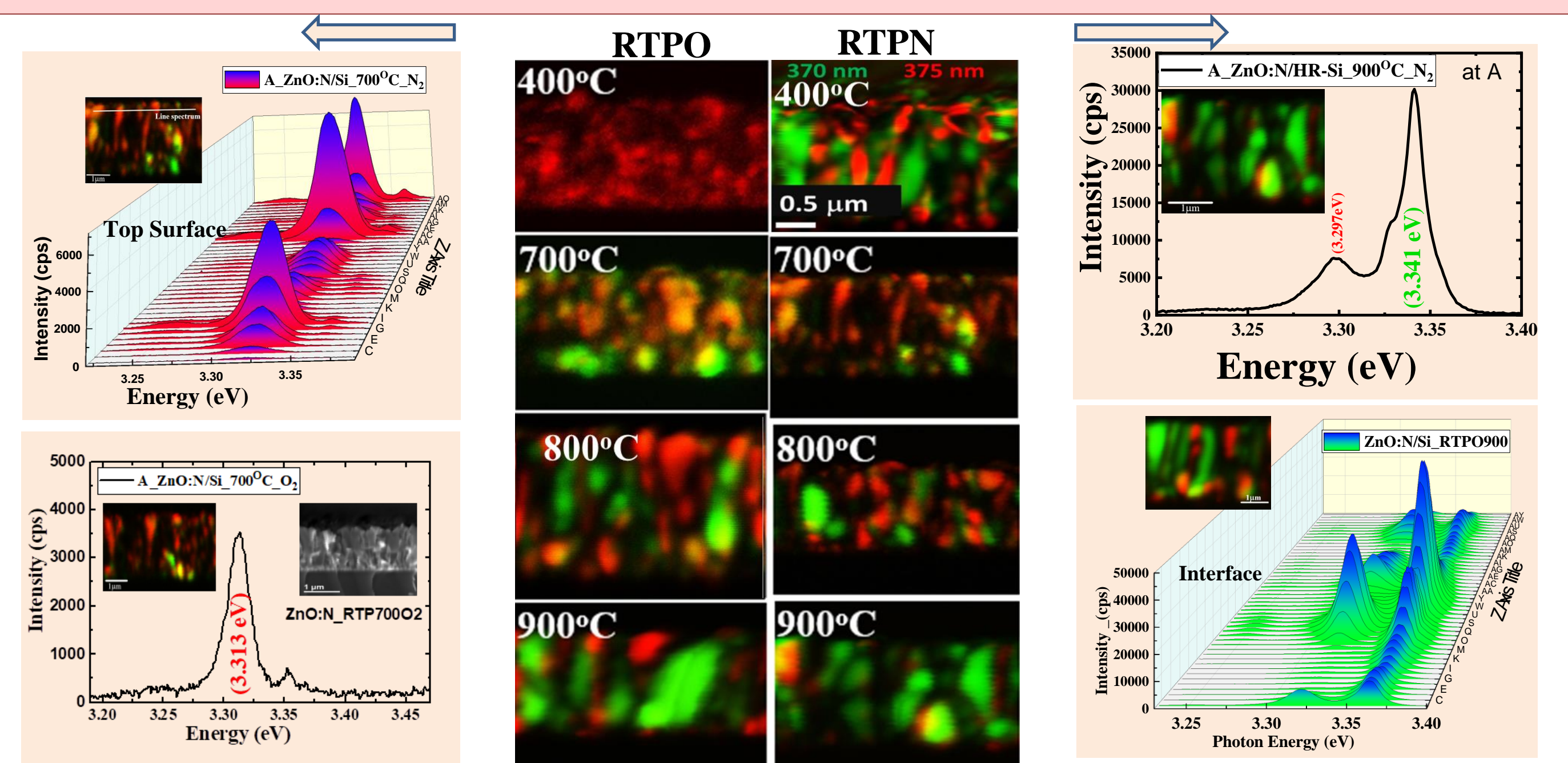
- ❖ LT-CL spectra and SEM images were recorded exactly at the same cross-section areas
- ❖ SEM and CL images were compared to relate the area of emission with the structure of the films.



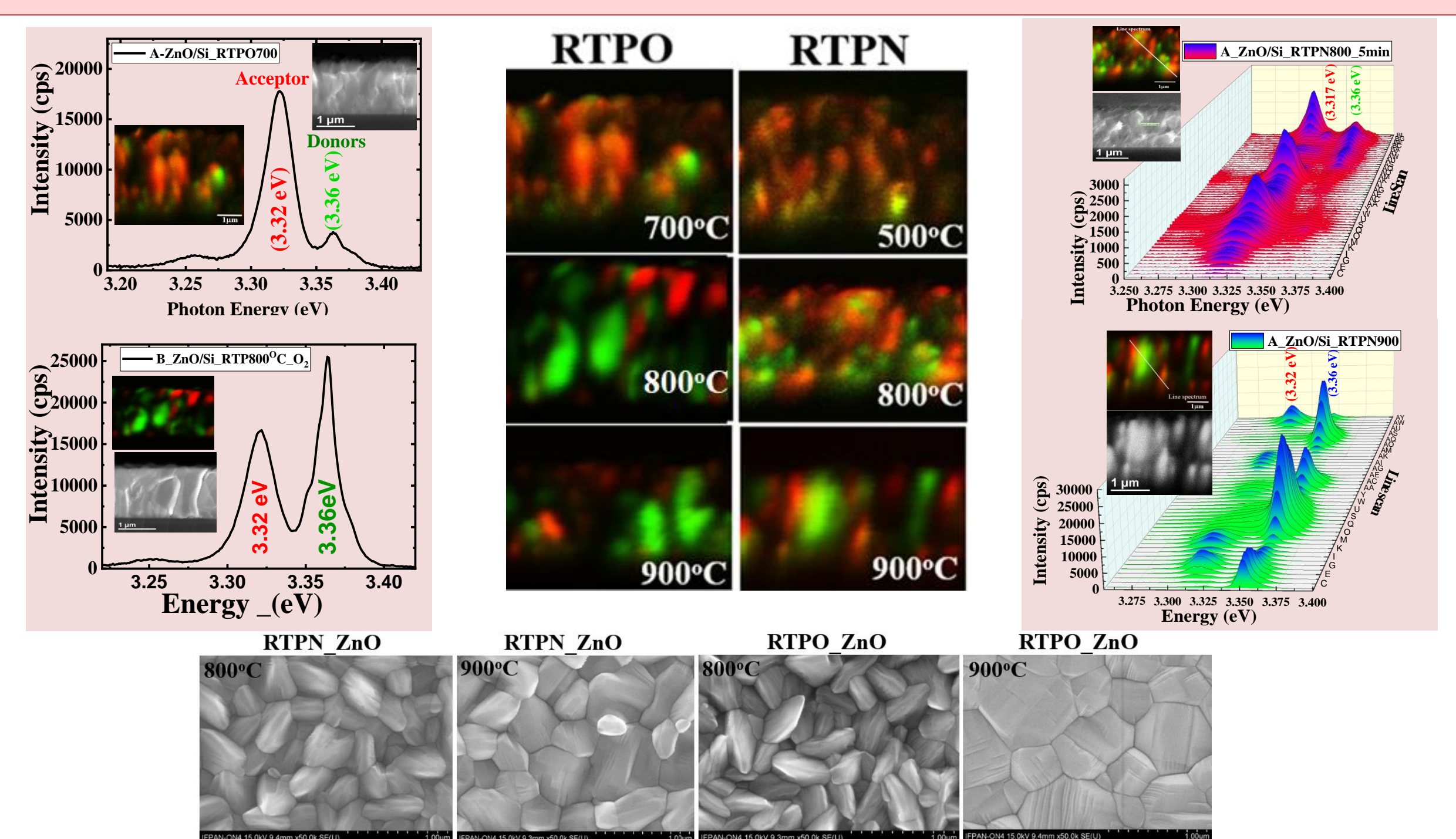
Experimental

1. Polycrystalline ~1.5μ thick ZnO/Si(HR) and ZnO:N/Si(HR) films were deposited at 100°C (O-rich conditions) by ALD using the same deposition parameters
2. Two types of substrates, HR-Si(100), 5000Ωcm (324μ) and 10000 Ω cm(525 μ) used for ZnO and ZnO:N deposition
3. RTA post-growth annealing at six temperature (400 – 900°C) under N₂/O₂ atm. for 5 min.
4. Measurements:
 - XRD → orientation and size of crystallites
 - SIMS → H and C concentrations
 - LT-CL → intensity of acceptor/donor related emission in ZnO and ZnO:N
 - RT-Hall → electrical characteristic of the films (carrier concentration, resistivity and mobility)

ZnO:N



ZnO



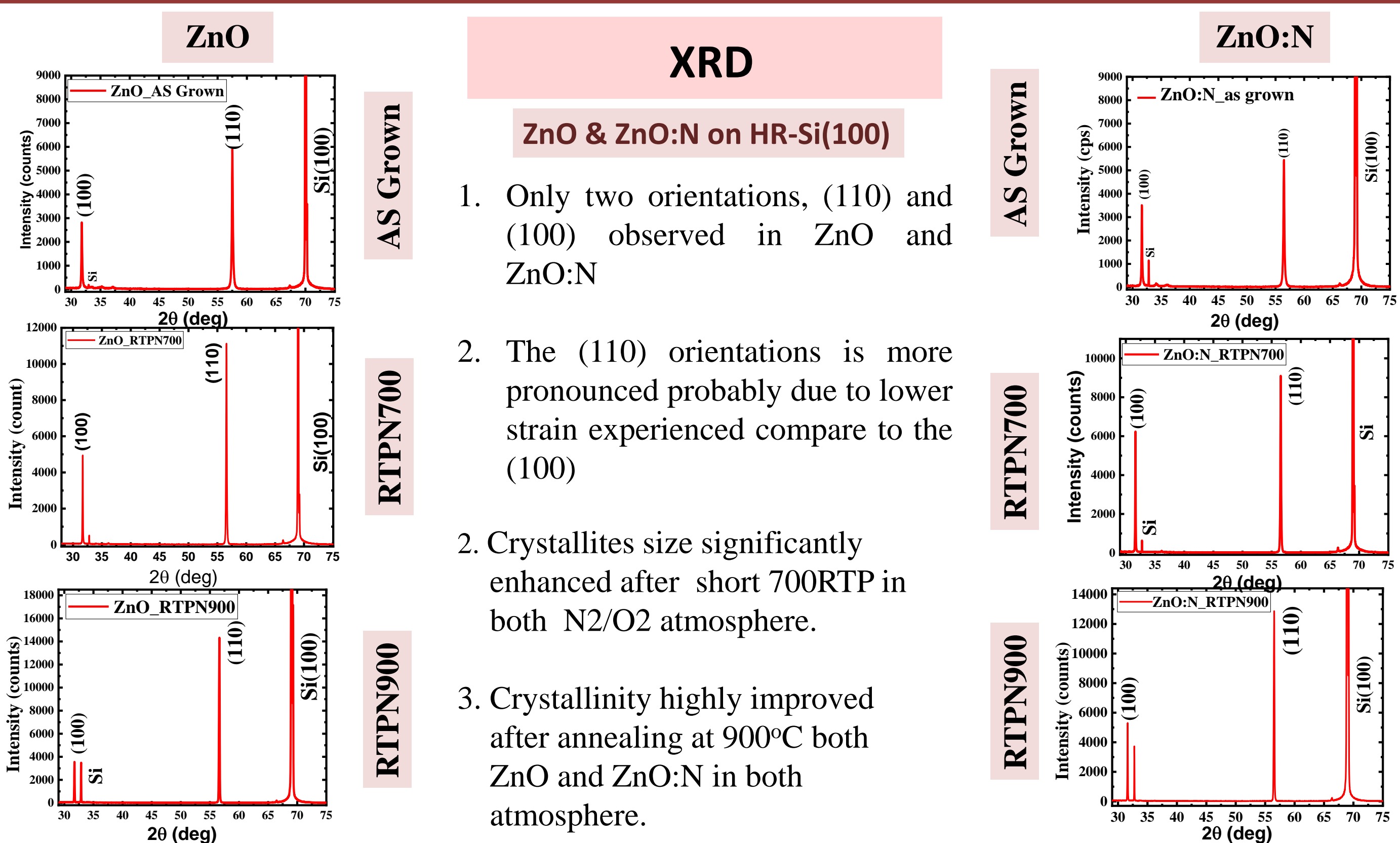
Conclusions

- ❑ LT-CL maps of ZnO and ZnO:N provide a complex picture in which acceptor- and donor-related CL separated and generally produced from distinct crystallites.
- ❑ Near band edge (NBE) CL is very weak in case of as grown films as well as films annealed at low temperature and also for higher N doping (> 10¹⁹at/cm³) and high impurity concentration
- ❑ H concentration drops from 10²⁰at/cm³ to 10¹⁸at/cm³ after RTP >600°C in both atmospheres; it was found to depend on resistivity as well as thickness of the silicon substrate (strain?)
- ❑ Both the annealing temperature and medium influenced the acceptor- and donor-related CL of ZnO and ZnO:N films, since they affect the concentration of N dopant, H and C- impurities as well as structural features of the films like strain and crystallite size
- ❑ Acceptor related CL emission is observed only for films annealed below 800°C; at 900°C annealing, more donors than acceptors get activated
- ❑ H impurity level is similar in as grown ZnO:N and ZnO, but it is 2-3 times higher for ZnO:N than ZnO after 700-900°C RTA which clearly indicates the presence of N-H bond and related complexes in ZnO:N films
- ❑ Scanning photoelectron microscopy study (SPEM) performed at Elettra Synchrotrone Trieste with a *state of the art* resolution of 130 nm confirms the presence of *p*-type and *n*-type regions inside the ZnO and ZnO:N films (see Tuesday poster session TuPA27, Electronic Structure of Acceptor Complexes in ZnO:N bulk and nanocrystals – DFT Calculations and Scanning Photoelectron Spectroscopy)

References:

- [1] Guzewicz et al., ACS Applied Materials & Interfaces 9 (31), 26143-26150, 2017.
- [2] Mishra et al., "Structural Properties of Thin ZnO Films Deposited by ALD under O-Rich and Zn-Rich Growth Conditions and Their Relationship with Electrical Parameters" Materials 14.14 (2021): 4048.
- [3] Guzewicz, Volnianska et al., Valence Band Electronic Structure of ZnO and ZnO:N – Experimental and Theoretical Evidence of Defect Complexes, Phys. Rev Applied (under revision)

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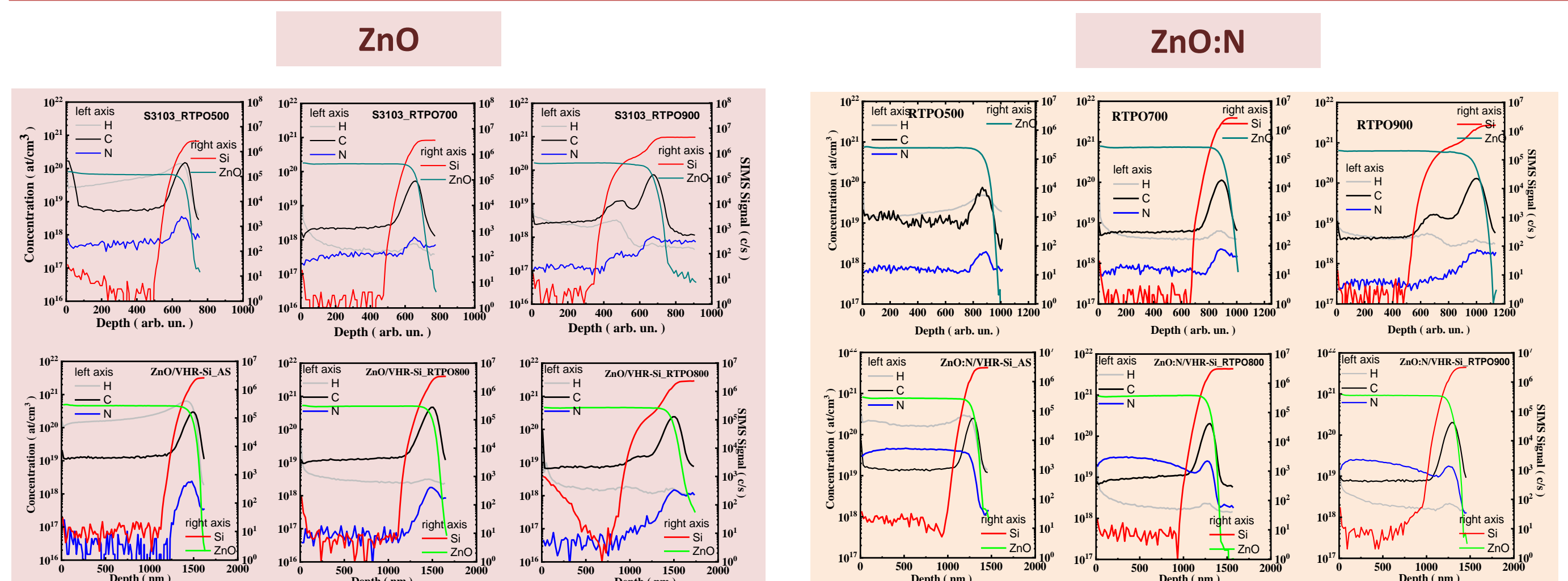


XRD

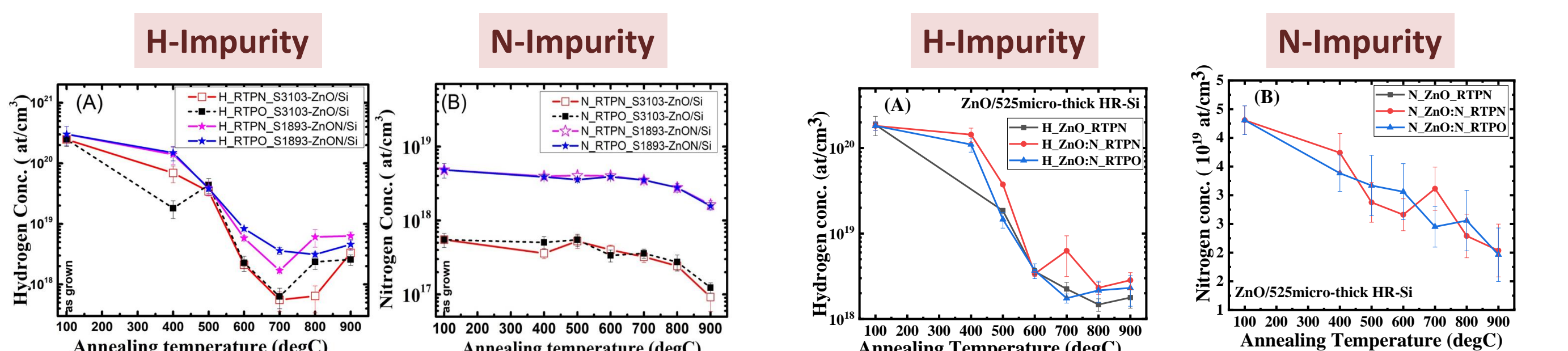
ZnO & ZnO:N on HR-Si(100)

1. Only two orientations, (110) and (100) observed in ZnO and ZnO:N
2. The (110) orientations is more pronounced probably due to lower strain experienced compare to the (100)
2. Crystallites size significantly enhanced after short 700RTP in both N₂/O₂ atmosphere.
3. Crystallinity highly improved after annealing at 900°C both ZnO and ZnO:N in both atmosphere.

Impurities in-incorporation (SIMS)



1. Hydrogen impurities decreased up to two orders of magnitude after RTP>600°C temperature in both atmospheres
2. H-impurity is higher in case of ZnO:N annealed in N₂ atmosphere as compared to O₂ atmosphere
3. Nitrogen concentration in ZnO:N films does not depend on annealing atmosphere
4. Carbon concentration is at the level of 10²⁰at/cm³ (lower in ZnO:N as compared to ZnO) and decreases to 10¹⁹at/cm³ after RTP>600°C in both atmospheres



ZnO & ZnO:N on HR-Si(100)

ZnO & ZnO:N on VHR-Si(100)